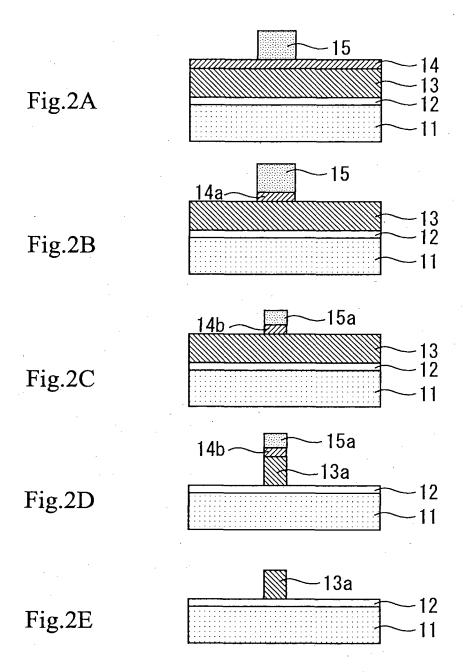


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Fig.3A

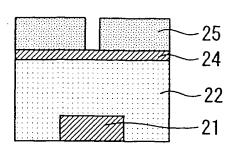


Fig.3B

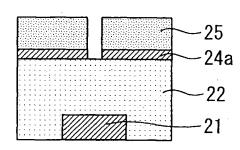


Fig.3C

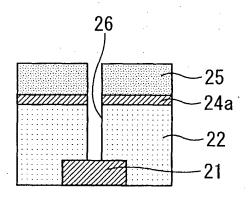
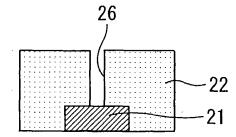


Fig.3D



Title: METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE THROUGH USE OF MASK MATERIAL Inventors: Takeshi MATSUNUMA
Atty Docket No.: 402729
Leydig, Voit & Mayer 202-737-6770

Background Art



